Oxford 82 Etcher

Manager: Meredith Metzler
Backup: Vince Genova
Calls to staff phones will be automatically forwarded to their cell phones during accessible hours. At other times leave a message or send them an email.

Work Phone
254-4934
254-4907

Safety
- No unusual hazards during normal operation
- No buddy system restrictions imposed on normal operation

Process Restrictions
Material Restrictions
- Only CMOS compatible materials - Si, SiO2, Si3N4, refractory metals, standard resists
- No gold or silver etching
- No high vapor pressure materials (lead, indium, ITO)
- No microscope slides

Parameter Restrictions
- Do not exceed 300 W RF power

Scheduling / Sign-up Restrictions
- Maximum 2 hour block reservation
- Maximum 2 reservations in advance at any time

Requirements (Do Every Time)
- You must remain in the laboratory near the instrument or have an authorized user designated to do so

Prohibitions (Never Do)
- Do not clean the electrode or chamber with solvents. Report to manager.

Common Problems

<table>
<thead>
<tr>
<th>Problem:</th>
<th>Root Cause:</th>
<th>Solution:</th>
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Other Comments or Cautions